



Bucket No.: 1268-093A

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Moshe FINAROV

U.S. Patent Application No. 09/626,793

Filed: July 26, 2000

:  
:  
: Confirmation No. 8657  
:  
: Group Art Unit: 2851  
:  
: Examiner: D. Esplin

For: APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR  
PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A  
METHOD FOR USE THEREOF

**REQUEST FOR CORRECTED FILING RECEIPT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached is a copy of the Official Filing Receipt received from the U.S. Patent and Trademark Office in the above-referenced application, on which we noticed that the following information has been omitted:

- 1) Foreign Application: Israel Application No. 126949, filed November 8, 1998
- 2) Domestic Priority: PCT/IL99/00598, filed November 7, 1999

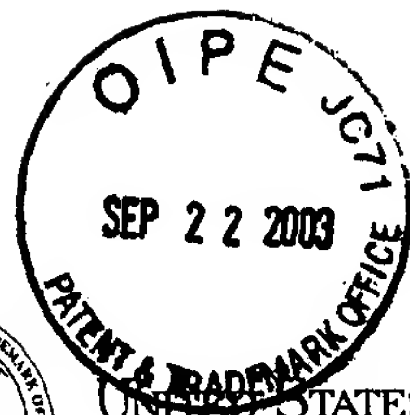
A copy of the Declaration *as filed* is also attached. It is requested that a corrected filing receipt be issued.

Respectfully submitted,

**LOWE HAUPTMAN GILMAN & BERNER, LLP**

Benjamin J. Hauptman  
Registration No. 29,310

1700 Diagonal Road, Suite 300  
Alexandria, Virginia 22314  
703-684-1111 BJH/klb  
Facsimile: 703-518-5499  
Date: September 16, 2003



UNITED STATES PATENT AND TRADEMARK OFFICE

COMMISSIONER FOR PATENTS  
UNITED STATES PATENT AND TRADEMARK OFFICE  
WASHINGTON, D.C. 20231  
www.uspto.gov

APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/626,793	07/26/2000	2872	410	1268-093A	12	15	2

CONFIRMATION NO. 8657

## FILING RECEIPT



\*OC000000005696528\*

Lowe Hauptman Gopstein Gilman & Berner LLP  
Suite 310  
1700 Diagonal Road  
Alexandria, VA 22314

JAN 29 2001

Date Mailed: 01/22/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the PTO processes the reply to the Notice, the PTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

Moshe Finarov, Rehovot, ISRAEL;

## Continuing Data as Claimed by Applicant

THIS APPLICATION IS A CIP OF 09/509,080 05/22/2000

## Foreign Applications

If Required, Foreign Filing License Granted 09/18/2000

Projected Publication Date:

Non-Publication Request: No

Early Publication Request: No

\*\* SMALL ENTITY \*\*

## Title

Apparatus for integrated monitoring of wafers and for process control in the semiconductor manufacturing and a method for use thereof

## Preliminary Class

359

Data entry by : SCOTT, JOSEPH

Team : OIPE

Date: 01/22/2001

